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AMENDMENT TRANSMITTAL LETTER (Large Entity) Applicant(s): Ju-Cheol SHIN et al.						Docket No. SEC.828D	
Application No. 10/601,561	Filing Date June 24, 2003	Examiner Karla A. Moore		20987		Group Art Unit 1763	7739
Invention C CHEMICAL VAPOR DEPOSITION METHOD FOR DEPOSITING SILICIDE AND APPARATUS FOR PERFORMING THE SAME							
COMMISSIONER FOR PATENTS:							
Transmitted herewith is an amendment in the above-identified application. The fee has been calculated and is transmitted as shown below.							
		CLAIMS AS AM	IENDEC)			
	CLAIMS REMAINING	HIGHEST#		ER EXTRA	T		ADDITIONAL
	AFTER AMENDMENT	PREV. PAID FOR		PRESENT		RATE	FEE
TOTAL CLAIMS	8 -	20 =	·	0	х	\$50.00	\$0.00
INDEP. CLAIMS	1 -	3 =		0	x	\$200.00	\$0.00
Multiple Dependent	t Claims (check if appl	licable)					\$0.00
		TOTAL ADDITIONAL F	FEE FO	R THIS AMI	END	MENT	\$0.00
No additional fee is required for amendment. Please charge Deposit Account No. in the amount of A check in the amount of to cover the filing fee is enclosed. The Director is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account Any additional filing fees required under 37 C.F.R. 1.16. Any patent application processing fees under 37 CFR 1.17. Payment by credit card. Form PTO-2038. WARNING: Information on this form may become public. Credit card information should not be included on this form. Provide credit card information and authorization on PTO-2038.							
Dated: FEBRUARY 8, 2005 Signature STEPHEN R. WHITT REG. NO. 34,753 VOLENTINE FRANCOS & WHITT, PLLC ONE FREEDOM SQUARE 11951 FREEDOM DRIVE, SUITE 1260 RESTON, VA 20190 TEL. 571.283.0720 Dated: FEBRUARY 8, 2005 I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to "Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450" [37 CFR 1.8(a)] on (Date)							
cc:	Signature of Person Mailing Correspondence Typed or Printed Name of Person Mailing Correspondence						



Application No. 10/601,561 Attorney Docket No. SEC.828D Amendment Filed February 8, 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of

Ju-Cheol Shin et al. : Group Art Unit: 1763

Application No. 10/601,561 : Examiner Karla A. Moore

Filed: June 24, 2003

For: CHEMICAL VAPOR DEPOSITION METHOD FOR DEPOSITING SILICIDE AND

APPARATUS FOR PERFORMING THE SAME

AMENDMENT

U.S. Patent and Trademark Office Customer Service Window, Mail Stop Amendment Randolph Building 401 Dulany Street Alexandria VA 22314

Sir:

In response to the Office Action of November 9, 2004, please amend the above-identified application as follows:

Amendments to the Title begin on page 3 of this paper.

Amendments to the Specification begin on page 4 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 5 of this paper.

Amendments to the Abstract begin on page 7 of this paper.

Remarks/Arguments begin on page 8 of this paper.

Amendments to the Title

Please replace the Title of the Invention with the following new title:

CHEMICAL VAPOR DEPOSITION APPARATUS FOR DEPOSITING
SILICIDE